

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of  
K. Yuda et al.

Application. No.: 09/818,972

Filed: March 27, 2001

For: **METHOD OF FORMING SILICON  
OXIDE FILM AND FORMING  
APPARATUS THEREOF**

Art Unit: 1762

Examiner: Unassigned

Docket No.: GOM-02001

**Certificate of Mailing**

I hereby certify that this correspondence is being deposited with the U.S. Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, Washington, DC 20231, on June 27, 2001.

  
Tracey A. Newell

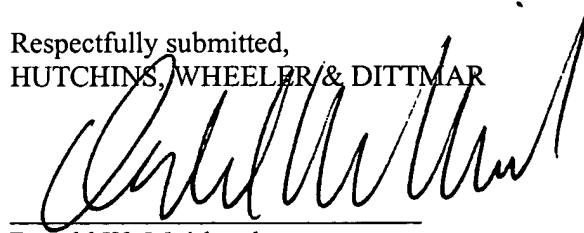
**TRANSMITTAL OF FORMAL DRAWING**

Sir:

Applicant hereby submits three drawing sheets containing Figs. 1-6 in the above-referenced patent application.

Should there be any questions after reviewing this paper, the Examiner is invited to contact the undersigned at (617) 951-6676.

Respectfully submitted,  
HUTCHINS, WHEELER & DITTMAR

  
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June 27, 2001

Date

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